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(Use several sheets if necessary)

Application Number

10/046,594

Stephen Y. Chou

October 29, 2001

1732

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M. Vargot

7/2/07
PEP Section 609:

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-A820 (also form PTO-1449)

 <p>INFORMATION DISCLOSURE CITATION <i>Use several sheets if necessary</i></p>	Docket Number (Optional) U6090-3	Application Number 10/046,594
	Applicant(s) Stephen Y. Chou	
	Filing Date October 29, 2001	Group Art Unit 1732

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner

Date Considered

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Stephen Y. Chou	
FILING October 29, 2001	GROUP 1732

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

MOV			Tan, H., et al., "Roller Nanoimprint Lithography" Vac. Sci. Technol. B 16 (6) Nov/Dec 1998.
MOV			Feynman, Richard, "There's Plenty of Room at the Bottom-An Invitation to Enter a New Field of Physics" talk delivered at the annual meeting of the American Physical Society at the California Institute of Technology (Caltech) in 1959, published in February 1960 issue of Caltech's "Engineering and Science".

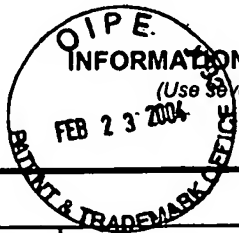
EXAMINER

² M. Vargot

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*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

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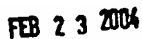
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

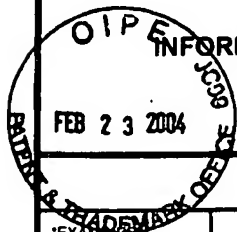
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Nov		Aumiller et al., "Submicrometer Resolution Replication of Relief Patterns for Integrated Optics", J. Appl. Phys., Vol. 45, pp. 4557-4562, (1974)
Nov		Nisper, "Injection-molded replication of binary optic structures", SPIE v2600 Oct 23-24, 1995 p. 56-64 0227-786X

EXAMINER <i>M. Vargot</i>	DATE CONSIDERED <i>7/2/07</i>
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1732**U.S. PATENT DOCUMENTS**

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FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*

W6V			Healey et al., "Photodeposition of Micrometer-scale polymer patterns on optical imaging Fibers" Science Vol. 269, August 1995, pp. 1078-1080.

EXAMINER
*M. Vung*DATE CONSIDERED
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Sheet 1 of *P*

Form 1449*	Atty. Docket No.: 600.426US2	Serial No. Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant: Stephen Y. Chou	
	Filing Date: Herewith	Group: Unknown

U.S. PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
MOV	3,743,842	07/03/1973	Smith, H.I., et al.	250	320	01/14/72
↑	4,310,743	01/12/1982	Seliger, R.L.	219	121 EB	09/24/79
↑	4,325,779	04/20/1982	Rossetti, J.J.	156	651	11/17/80
↑	4,383,026	05/10/1983	Hall, T.M.	430	325	08/24/81
↑	4,450,358	05/22/1984	Reynolds, G.O.	250	492.1	09/22/82
↑	4,498,009	02/05/1985	Reynolds, G.O.	250	452.1	09/22/82
↑	4,516,253	05/07/1985	Novak, W.T.	378	034	04/25/83
↑	4,552,615	11/12/1985	Amendola, A., et al.	158	659.1	05/21/84
↑	4,576,678	03/18/1986	Shibata, H.	156	643	09/13/84
↑	4,606,788	08/19/1986	Moran, P.L.	156	656	04/03/85
↑	4,731,155	03/15/1988	Napoli, L.S., et al.	156	643	04/15/87
↑	4,832,790	05/23/1989	Rossetti, J.J.	156	651	02/24/87
↑	5,277,749	01/11/1994	Griffith, J.H., et al.	156	643	10/17/91
MOV	5,861,113	01/19/1999	Choquette, S.J., et al.	264	1.24	08/01/96

FOREIGN PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes	No
MOV	1196749	01/30/1988	European	G11B	7/26		
↑	244884	03/28/1986	European	B29C	33/64		
↑	401196749	08/08/1989	Japan	G11B	7/26		
↑	4255307	09/10/1992	Japan	B29C	33/38		
↑	4332694	08/05/1991	European	B41N	1/12		
↑	9117565	11/14/1991	PCT	H01L	21/00		
MOV	98/26913	06/25/1998	PCT	B29C	33/58		

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

MOV	Broere, et al., "250-A Linewidths with PMMA Electron Resist", <u>Applied Physics Letter 33 (5)</u> , 1978 American Institute of Physics, 392-394, (September 1, 1978)
↑	Chou, S.Y., et al., "Imprint Lithography with 25-Nanometer Resolution", <u>Science, Vol 272</u> , 85-87, (April 5, 1996)
↑	Early, K., et al., "Absence of Resolution Degradation in X-Ray Lithography for Wavelength from 4.5nm to 0.83nm", <u>Microelectronic Engineering 11</u> , Elsevier Science Publishers B.V., 317-321, (1990)
MOV	Fischer, et al., "10 nm Electron Beam Lithography and sub-50 nm Overlay Using a Modified Scanning Electron Microscope", <u>Applied Physics Letter 62 (23)</u> , 1993 American Institute of Physics, 2989-2991, (June 7, 1993)

Examiner

al. Vargab

Date Considered

7/2/07

*Substitute Disclosure Statement Form (PTO-1449)

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Sheet 2 of *P*

Form 1449*	Atty. Docket No.: 600.426US2	Serial No. Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant: Stephen Y. Chou	
	Filing Date: Herewith	Group: Unknown

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

**Examiner
Initial

MOV	Hara, et al., "An Alignment Technique Using Diffracted Moire Signals", <u>J. Vac. Sci. Technol. B 7 (6)</u> , 1989 American Vacuum Society, 1977-1979, (Nov./Dec. 1989)
↑	Harmening, et al., "Molding of Threedimensional Microstructures by the Liga Process", <u>Proceedings IEEE : Micro Electro Mechanical Systems</u> , Travemunde, Germany, 202-207, (1992)
↓	Li, et al., "Molding of Plastic Components Using Micro-EDM Tools", <u>IEEE/CHMT International Electronics Manufacturing Technology Symposium</u> , 145-149, (1992)
MOV	Nomura, et al., "Moire Alignment Technique for the Mix and Match Lithographic System", <u>J. Vacuum Society Technol. B 6 (1)</u> , American Vacuum Society, 394-398, (Jan/Feb 1988)

Examiner

M. Vargot

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*Substitute Disclosure Statement Form (PTO-1449)

**EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 209; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.